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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPL. NO. : 09/462,912 Confirmation No. 5646
APPLICANTS: Shigeo MORIYAMA, et al.
FILED : January 18, 2000
FOR : POLISHING APPARATUS AND METHOD FOR PRODUCING
SEMICONDUCTORS USING THE APPARATUS
ART UNIT : 3723
EXAMINER : Dung Van Nguyen
DOCKET NO.: 29273/516
CUSTOMER NO.: 23838

COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

SIR:

In response to the Final Office Action of July 7, 2004, the period for response having been extended herein to January 19, 2004 by payment of the requisite fee of \$980.00 for a Petition for Extension of Time Under 37 C.F.R. § 1.136(a), Applicants respectfully request that the Examiner reconsider his rejection in view of the remarks below. In addition, it is respectfully requested that the following clarifying amendment be entered to place this application in condition for allowance or better form for appeal.

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